VAKSiS

R&D AND ENGINEERING

ANGORA®

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PRODUCT INFORMATION

Vaksis ANGORA platform is composed of box-type vacuum chambers and involve the techniques and combinations below:

CONFIGURATION MATRIX

Techniques	Magnetron Sputtering (MS)	Thermal Evaporation (Th E)	Electron Beam (e-Beam)	Organic and Metal Evaporation (OLED/OPV)	Multi Tech.
ANGORA	✔	✔	✔	✔	MS, Th E, e-Beam, OLED/OPV

TECHNICAL SPECIFICATIONS

Ultimate Vacuum Pressure ..... ≤ $5x10^{-7}$Torr
Substrate Size ..... 4" diameter
Substrate Heating ..... max. 800°C
Substrate Rotation ..... 3-30 rpm
Cooling..... Where necessary
Deposition Mode ..... Upward
Thickness Measurement ..... In-situ measurement with Quartz X-tal Oscillator

POWER SOURCES

-DC and/or RF Power Supply for Sputtering Magnetron Source
-Effusion Cell A.C. Power Supply for Metal and/or Organic Evaporation Sources
-High-Current Low-Voltage A.C. Power Supply for Resistive Thermal Evaporation Source
-Power Supply for Electron Beam Evaporation Source

SOFTWARE

System operation by user-friendly software. It is not only the automation and control software but also coating management software which allows the user design his/her specific coating experiments, examine the process parameters used in the past, and use the recipes/coatings developed in the past without hustle.
Human and machine safeties are prime importance in the operations performed by the software. A graphical user interface will allow the user to see the status of the system during operation.

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